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(12) **United States Design Patent**  
**Kaneko et al.**

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(54) **OUTER TUBE FOR PROCESS TUBE FOR MANUFACTURING SEMICONDUCTOR WAFERS**

(75) Inventors: **Hirofumi Kaneko**, Oshu (JP); **Atsushi Endo**, Nirasaki (JP)

(73) Assignee: **Tokyo Electron Limited**, Minato-Ku (JP)

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(30) **Foreign Application Priority Data**

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(51) **LOC (10) Cl.** ..... **13-03**

(52) **U.S. Cl.**  
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(58) **Field of Classification Search**  
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See application file for complete search history.

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*Primary Examiner* — Elizabeth J Oswecki

(74) *Attorney, Agent, or Firm* — Burr & Brown, PLLC

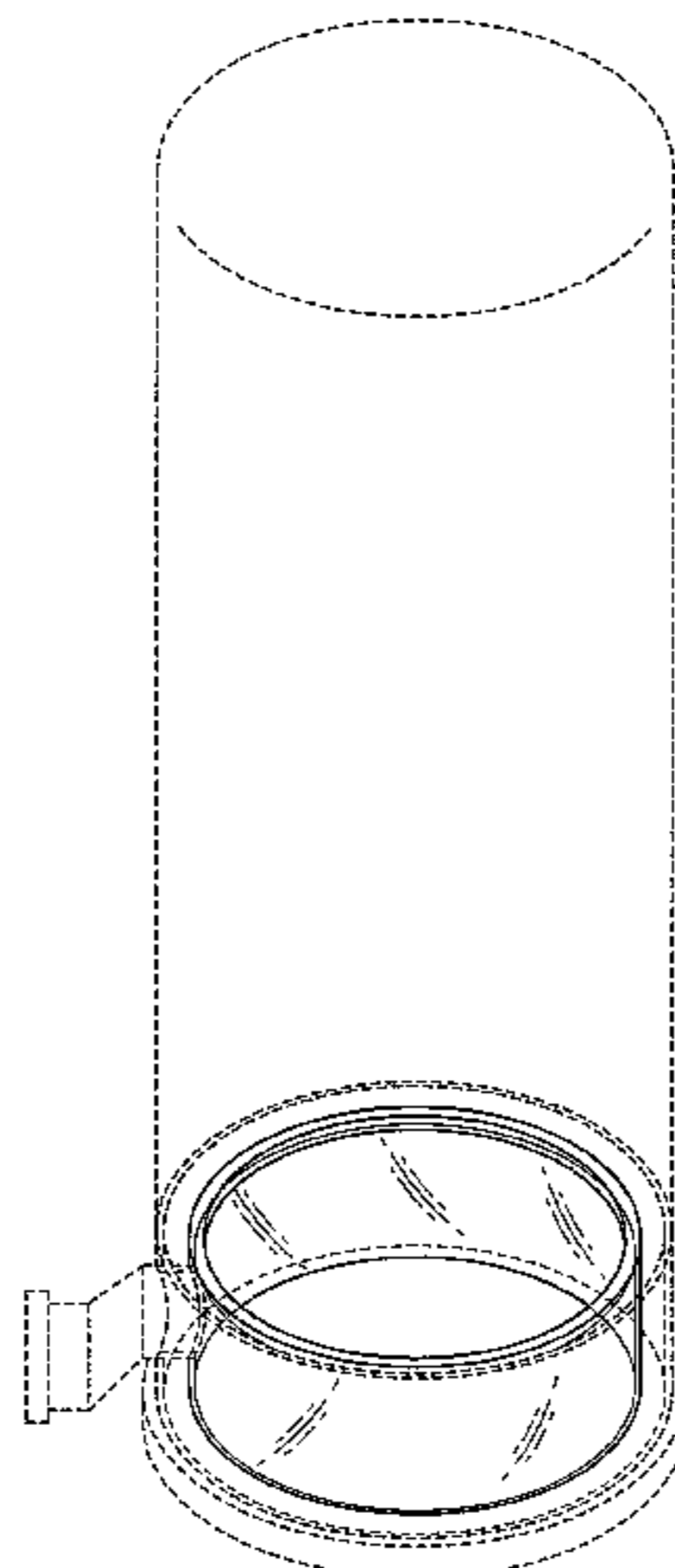
(57) **CLAIM**

The ornamental design for an outer tube for process tube for manufacturing semiconductor wafers, as shown and described.

**DESCRIPTION**

FIG. 1 is perspective view of an outer tube for process tube for manufacturing semiconductor wafers showing our new design;  
FIG. 2 is a front view thereof;  
FIG. 3 is a rear view thereof;  
FIG. 4 is a right side thereof;  
FIG. 5 is a left side view thereof;  
FIG. 6 is a top plan view thereof;  
FIG. 7 is a bottom plan view thereof; and,  
FIG. 8 is a cross-sectional view taken along line 8-8 of FIG. 6.  
The broken lines shown in the drawings represent portions of the outer tube for process tube for manufacturing semiconductor wafers that form no part of the claimed design.

**1 Claim, 7 Drawing Sheets**



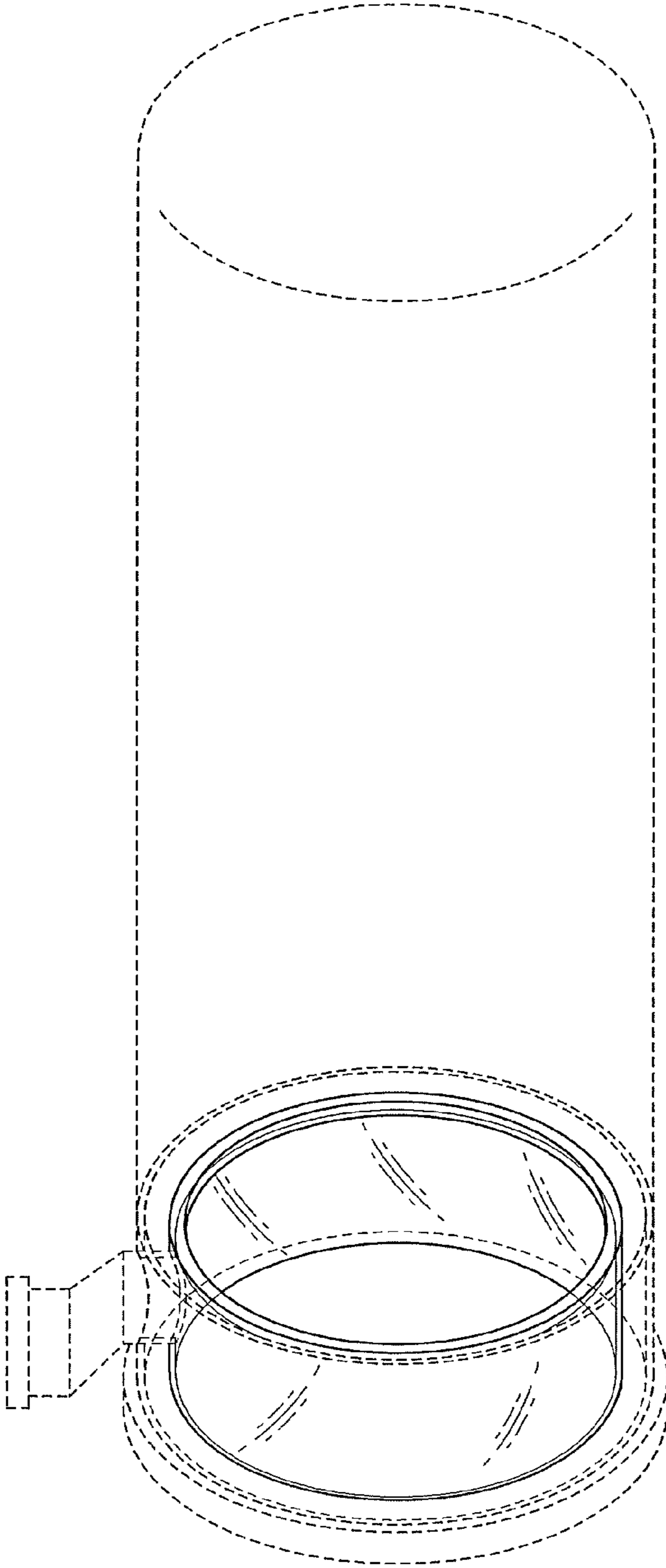


FIG. 1

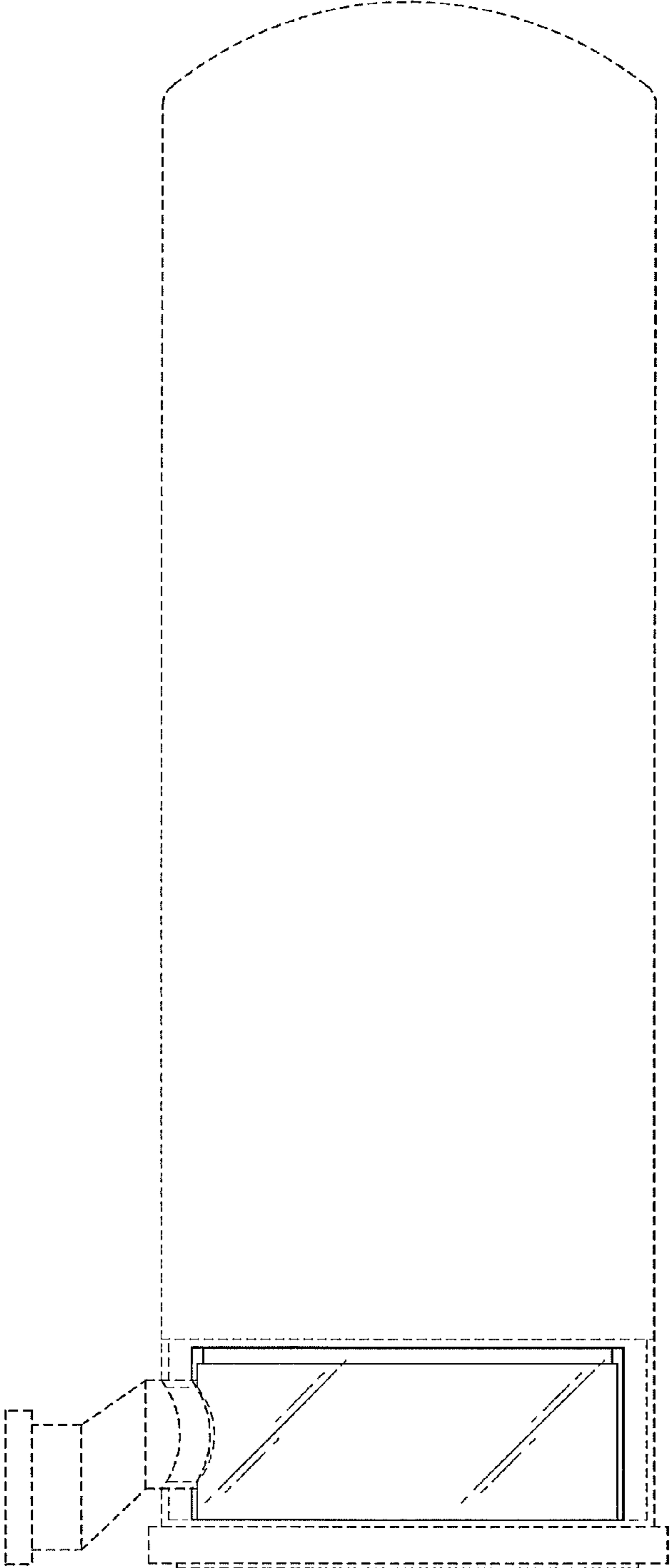


FIG. 2

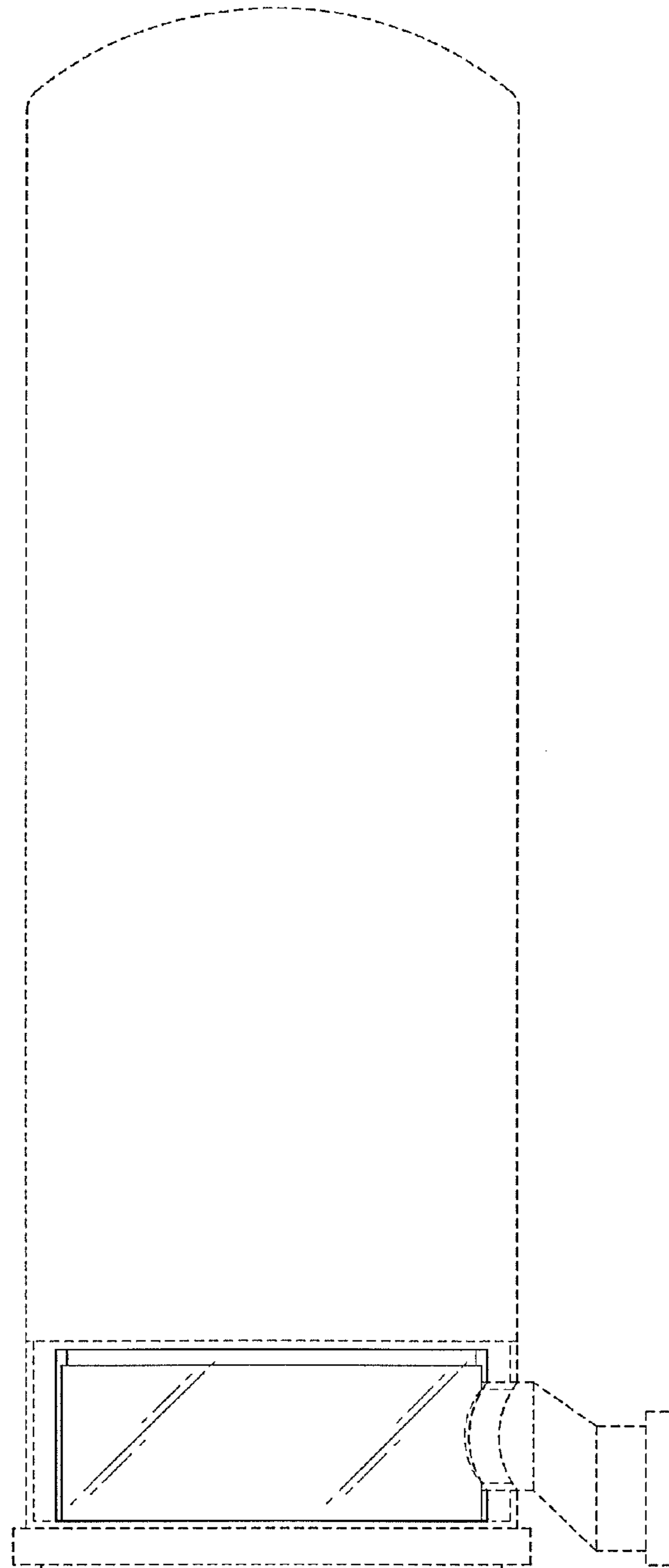


FIG. 3

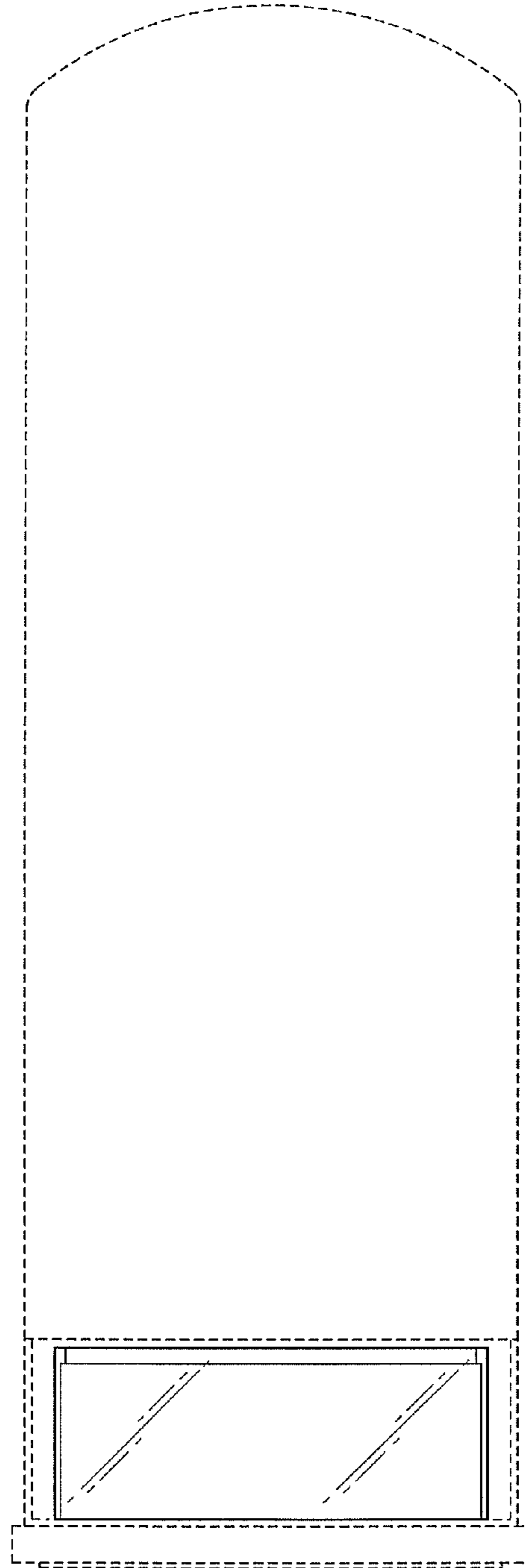


FIG. 4

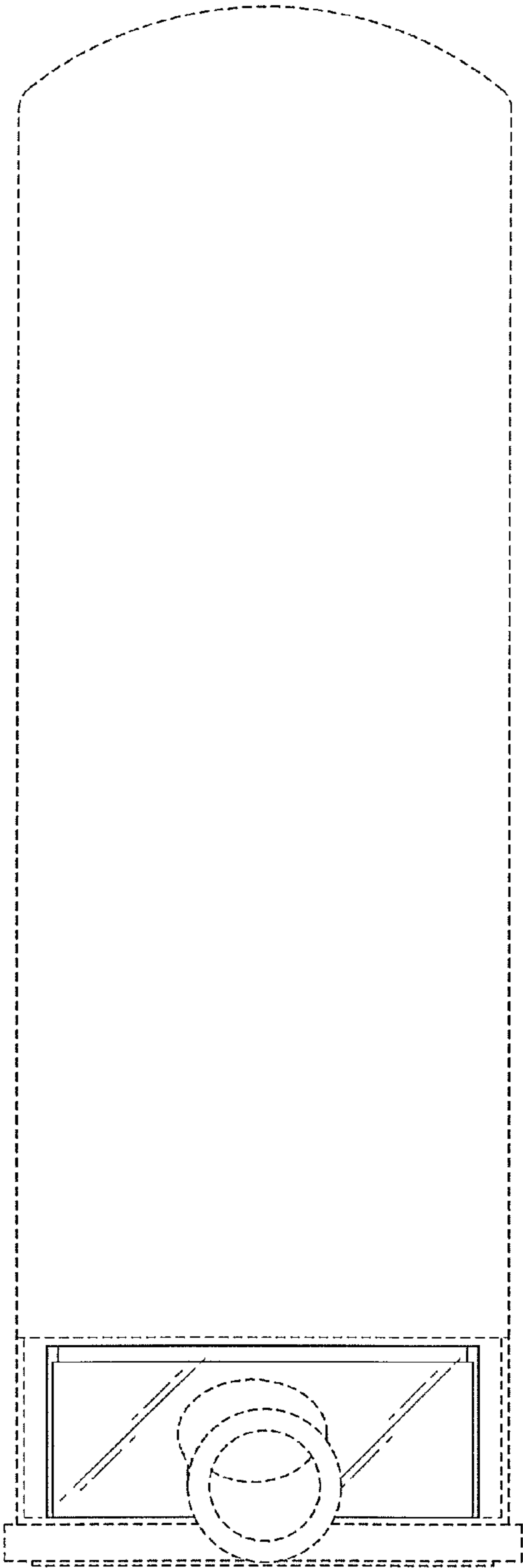


FIG. 5

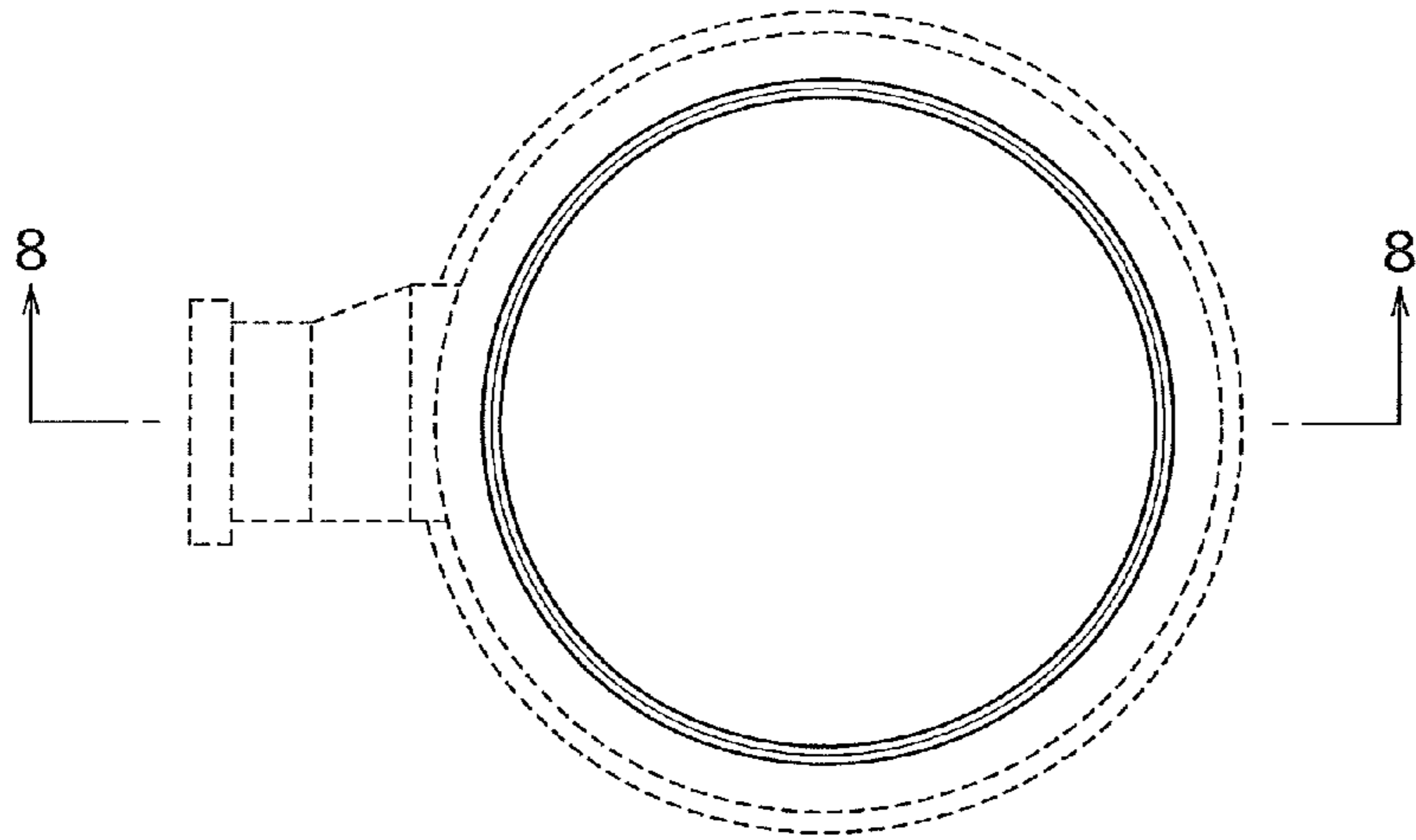


FIG. 6

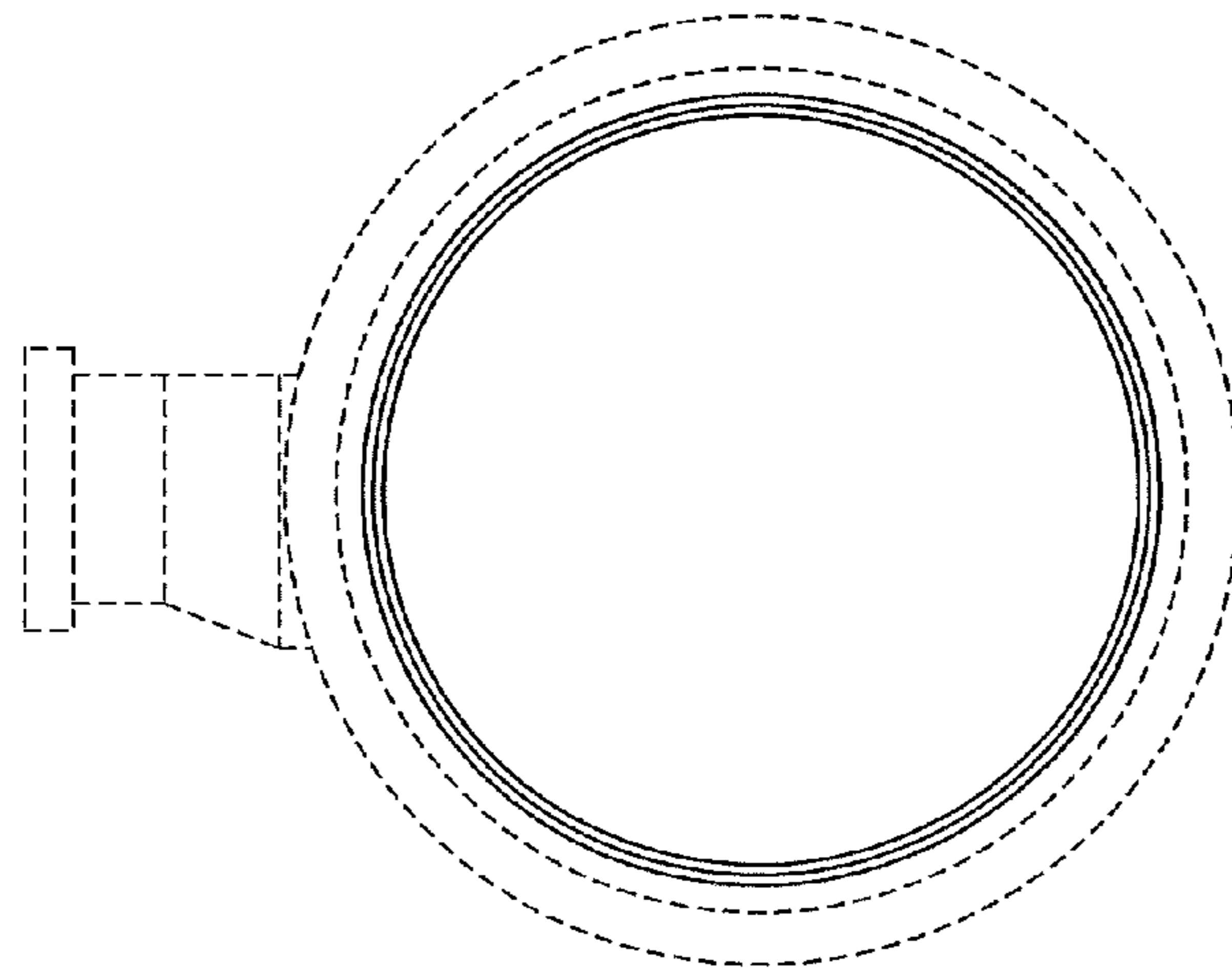


FIG. 7

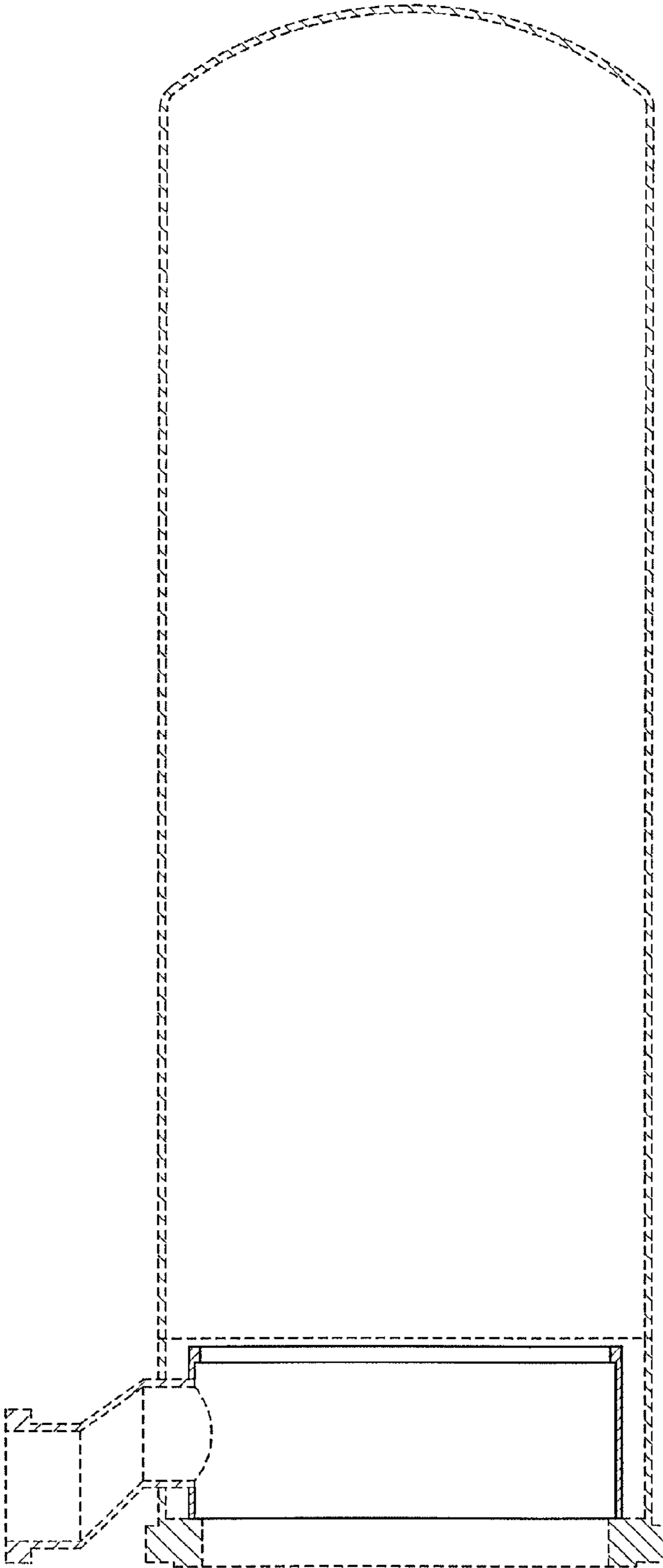


FIG. 8